Organosilicon Chemistry. Part XIII.¹ Insertion Reactions of 1,2,2-Trifluoroethylidene into Silicon-Hydrogen and Silicon-Halogen Bonds²

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1,2.2-Trifluoroethylidene, generated by the pyrolysis of 1.1,2,2-tetrafluoroethyltrifluorosilane. inserts exclusively into the silicon-hydrogen bond of trialkylsilanes R_3SiH ($R_3 = Et_3$, Et_2Me , or Me_3) or the silicon-deuterium bond of the silane Me₃SiD to afford the silanes CHF₂ CHF SiR₃ (98—99%) or CHF₂ CDF SiMe₃ (88%). With silanes X₃SICI (X₃ = Cl₃, Cl₂Me, CIMe₂, or Me₃) or Me₃SiBr insertion occurs into the silicon-halogen bond to give the silanes CHF₂·CFCI·SiX₃ or CHF₂·CFBr·SiMe₃ (2—15%). The silane Me₂CISiH reacts exclusively by Si⁻H insertion (96%) but both Si⁻H and Si⁻CI insertion (total *ca*. 55%) are observed with the silanes Cl₃SiH and MeCl₂SiH. Reaction of the carbene with dimethylvinylsilane and allyldimethylsilane gives products (99%) resulting from both Si-H insertion and double-bond addition (ratios 93: 7 and 67: 33, respectively), but with trichlorovinylsilane only addition to the double bond takes place (66%).

THERMAL decomposition of 1,1,2,2-tetrafluoroethyltrifluorosilane (I) at 150 °C takes place via an α -elimination process to afford silicon tetrafluoride and 1,2,2-trifluoroethylidene (II).^{3,4} In the absence of a reactive substrate, e.g. an olefin, the carbene (II) rearranges to trifluoroethylene,⁴ and addition of unchanged carbene (II) to trifluoroethylene then affords cis- and trans-1-difluoromethyl-1,2,2,3-tetrafluorocyclopropane (III). The amount of silicon tetrafluoride formed in reactions

$$\begin{array}{c} \mathrm{CHF}_{2} \cdot \mathrm{CF}_{2} \cdot \mathrm{SiF}_{3} \xrightarrow{\mathrm{I50} \, ^{\circ}\mathrm{C}} & \mathrm{SiF}_{4} + \mathrm{CHF}_{2} \cdot \ddot{\mathrm{CF}} \longrightarrow \mathrm{CHF} \cdot \mathrm{CF}_{2} \\ \mathrm{(I)} & (\mathrm{II}) \\ \end{array}$$
$$\begin{array}{c} \mathrm{CHF} \cdot \mathrm{CF}_{2} + (\mathrm{II}) \longrightarrow & \overline{\mathrm{CHF} \cdot \mathrm{CF}_{2} \cdot \mathrm{CF} \cdot \mathrm{CHF}_{2}} \\ \mathrm{(III)} \end{array}$$

involving thermal decomposition of the silane (I) provides an accurate measure of the extent of formation of the carbene (II).

Previous studies have shown that the carbene (II) reacts with olefins to give cyclopropanes in high yield,^{5,6} inserts into the Si-H bond of Me₃SiH to give CHF₂-CHF·SiMe₃,⁶ and inserts into the C-H bonds of alkanes in the order of reactivity tertiary > secondary > primary.⁶ The carbene (II), formed as described above, reacts in the singlet state, as shown by (i) exclusive stereospecific addition to both cis- and trans-but-2-ene⁶ and (ii) insertion into the tertiary C-H bond of the optically active ether L-CH₃[CH₂]₅·CHMe·OMe with complete retention of configuration.7 Theoretical calculations of the preferred conformations⁸ for the related series of carbenes $\ddot{C}F_2$, $\ddot{C}HF$, CF_3 , $\ddot{C}H$, and $(CF_3)_2\ddot{C}$ have indicated singlet states with R-C-R bond angles of ca. 110°.

In the present work the reactions of the carbene (II) with the silanes R_3SiH ($R_3 = Et_3$, Et_2Me , or Me_3), Me₃SiD, X₃SiCl (X₃ = Cl₃, Cl₂Me, ClMe₂, or Me₃), Me₃SiBr, X₃SiH (X₃ = Cl₃, Cl₂Me, or ClMe₂), X₃Si·CH:-¹ Part XII, R. N. Haszeldine, R. V. Parish, and R. J. Taylor,

J.C.S. Dalton, 1974, 2311. ² Preliminary communication, R. N. Haszeldine, A. E. Tipping, and R. O'B. Watts, *Chem. Comm.*, 1969, 1364. ³ W. I. Bevan, R. N. Haszeldine, and J. C. Young, *Chem. and Ind.*, 1961, 789; R. N. Haszeldine, P. J. Robinson, and R. F. Simmong J. Chem. Soc. 1964, 1900. Simmons, J. Chem. Soc., 1964, 1890.
 G. Fishwick, R. N. Haszeldine, C. Parkinson, P. J. Robinson,

and R. F. Simmons, Chem. Comm., 1965, 382.

 CH_2 ($X_3 = Cl_3$ or Me_2H), and $Me_2SiH \cdot CH_2 \cdot CH \cdot CH_2$ have been investigated.

Reaction of the Carbene (II) with Trialkylsilanes.—The thermal decomposition of the carbene precursor (I) at 150 °C in the presence of triethylsilane, diethylmethylsilane, or trimethylsilane (1:3 molar ratio) afforded silicon tetrafluoride (100%), unchanged trialkylsilane (67%)recovered), trifluoroethylene (1-2%), and products of the type CHF_2 ·CHF·SiR₃ (IV) (R₃ = Et₃, Et₂Me, or Me₃) (98-99%), formed by insertion into the Si-H bonds. Products formed by the insertion of (II) into C-H bonds were not detected.

The products (IV) were identified by n.m.r. spectroscopy; the low-field region of the ¹H n.m.r. spectra showed two absorptions of equal intensity centred at $\tau 3.97 - 4.02$ (CHF₂) and 5.40 - 5.55 (CHF), and the highfield region showed absorptions ($\tau 8.8-9.8$) for methylene and methyl protons in the methyl and ethyl groups. The ¹⁹F n.m.r. spectra showed absorptions at ca. 47 (CHF₂) and ca. 165 p.p.m. (CHF) to high field of trifluoroacetic acid. The adjacent asymmetric centre makes the two fluorine nuclei of the CHF₂ group magnetically non-equivalent; consequently they exhibit an AB pattern. However, the outer bands of the AB pattern were not observed and so J_{AB} could not be determined. The chemical shifts of the hydrogen and fluorine nuclei of the CHF₂·CHF·Si group and the observed coupling constants are in agreement with previously determined values.9

The insertion of methylene, formed by decomposition of diazomethane, into Si-H bonds was reported in

$$\begin{array}{c} \mathrm{PhSiH}_3 + \mathrm{CH}_2\mathrm{N}_2 \longrightarrow \mathrm{PhSiH}_2\mathrm{Me} + \mathrm{PhSiHMe}_2 \\ (70\%) & (5\%) \end{array}$$

1962.10 Since then Seyferth and his co-workers have

⁵ R. N. Haszeldine and J. G. Speight, unpublished results; J. Lee, C. Parkinson, P. J. Robinson, and J. G. Speight, J. Chem. Soc. (B), 1967, 1125.

⁶ R. N. Haszeldine and J. G. Speight, Chem. Comm., 1967,

995. 7 J. M. Birchall, R. N. Haszeldine, and T. K. Dempscy, unpublished results.

⁸ R. Hoffmann, G. D. Zeiss, and G. W. Van Dine, J. Amer. Chem. Soc., 1968, 90, 1485.

9 D. Cooper, R. N. Haszeldine, and M. J. Newlands, unpublished results.

10 K. Kramer and A. N. Wright, J. Chem. Soc., 1963, 3604.

studied extensively the synthetic and mechanistic aspects of the insertion of mercurial-derived dihalogenocarbenes into the Si-H bonds of trialkyl- and aryl-silanes,^{11,12} e.g.

$$\begin{array}{l} \mathrm{PhHg}\text{\cdot}\mathrm{CCl_2Br} + \mathrm{Et_3SiH} \longrightarrow \mathrm{Et_3Si}\text{\cdot}\mathrm{CHCl_2} + \mathrm{PhHgBr} \\ \mathrm{PhHg}\text{\cdot}\mathrm{CBr_3} + \mathrm{Ph_3SiH} \longrightarrow \mathrm{Ph_3Si}\text{\cdot}\mathrm{CHBr_2} + \mathrm{PhHgBr} \end{array}$$

Diphenylcarbene and ethoxycarbonylcarbene, formed by the decomposition of the corresponding diazo-compounds, also insert into Si-H bonds.13

It has been suggested ¹² that the insertion of dichlorocarbene into Si-H bonds takes place by a one-step reaction involving a slightly polar transition state of the type (V), formed by electrophilic attack of the carbene on the



Si-H bond, which collapses to give the observed products. Evidence for a transition state of type (V) has been provided by the retention of configuration observed in the products from insertion of the carbenes CCl₂ and ČBr, into the Si-H bond of the optically active methyl-(1-naphthyl)phenylsilane.¹⁴ In contrast the insertion of triplet diphenylcarbene into the Si-H bond of this silane results in racemic products formed via a two-step mechanism.14

It is considered probable that insertion of the carbene (II) into the Si-H bonds of the trialkylsilanes studied to give the products (IV) also takes place via an analogous one-step mechanism (Scheme 1).



The observation that the carbene (II) inserts into the tertiary C-H bond of isobutane in only 61% yield under analogous conditions⁶ indicates a lower reactivity of the tertiary C-H bond towards carbene (II) insertion than of the Si-H bond in trimethylsilane (99% yield). Products formed by insertion into the primary C-H bonds of the methyl groups were not observed in either case.

The silane CHF₂·CHF·SiMe₃, together with the isomeric silane $CH_2F \cdot CF_2 \cdot SiMe_3$ (ratio ca. 60:40), has previously been obtained by the photochemical addition of trimethylsilane to trifluoroethylene.⁹ It was therefore considered possible that the Si-H insertion products (IV) were formed via reaction of an excited trifluoroethylene species generated by rearrangement of the carbene (II). ¹¹ D. Seyferth and J. M. Burlitch, J. Amer. Chem. Soc., 1963,

85, 2667. ¹² D. Seyferth, R. Damrauer, J. Yick-Pui Mui, and T. J. Jula,

J. Amer. Chem. Soc., 1968, 90, 2944.

In order to determine if this were the case, decomposition of the carbene precursor (I) in the presence of an excess of deuteriotrimethylsilane was investigated. This gave silicon tetrafluoride (100%), trifluoroethylene (12%), and a single adduct (88%). The adduct was identified as having the structure CHF₂·CDF·SiMe₃ (VI) on the basis of its ¹H and ¹⁹F n.m.r. spectra; ¹H n.m.r. bands at $\tau 4.03$ (1H, td, CHF₂) and 9.83 (9H, SiMe₃) and ¹⁹F n.m.r. bands at 47.0 (2F, ABdd, CHF_AF_B) and 162.5 p.p.m. (1F, tdt, CDF) to high field of trifluoroacetic acid. The absence of a ¹H n.m.r. band for a CHF system and the observation that the ¹⁹F 162.5 p.p.m. band exhibited a 1:1:1 triplet splitting (110.0 Hz), assigned to geminal F-D coupling, showed conclusively that the adduct had structure (VI).

If an activated trifluoroethylene species were involved, the silanes (VII) and (VIII) would be expected to be formed by the sequence shown in Scheme 2. Since



adduct (VI) [and not adduct (VII) or (VIII)] was formed the reaction with both Si-D and Si-H bonds is considered to involve the carbene (II) as the reactive intermediate and not an activated trifluoroethylene species.

The yield of adduct (VI) (88%) is lower than that of adduct (IV) (99%) obtained from insertion into the Si-H bond of trimethylsilane. This indicates that, as expected, insertion into an Si-D bond is slightly less favourable than insertion into an Si-H bond.

Reactions of the Carbene (II) with Dimethylvinylsilane and Allyldimethylsilane.-The decomposition of the mercurial PhHg·CCl₂Br in a mixture of triethylsilane and cyclohexene has indicated that the Si-H bond is only 0.8 times as reactive as the olefinic double bond towards attack by dichlorocarbene.12 Reaction of diphenvlvinylsilane with dichlorocarbene afforded only the Si-H insertion product (IX), indicating that a double bond adjacent to silicon is considerably deactivated towards carbene attack.15

$$CH_2:CH \cdot SiPh_2H + CCl_2 \longrightarrow CH_2:CH \cdot SiPh_2 \cdot CHCl_2$$
(IX)

The present study of the comparative reactivities of the Si-H and C=C bonds in the silanes CH₂:CH·SiMe₂H and

A. Ritter and L. H. Sommer, International Symposium on Organosilicon Chemistry, Sci. Comm. Prague, 1965, 279.
 L. H. Sommer, L. A. Ulland, and A. Ritter, J. Amer. Chem.

Soc., 1968, 90, 4486. ¹⁵ D. Seyferth, J. M. Burlitch, H. Dertouzos, and H. D. Sim-

mons, J. Organometallic Chem., 1967, 7, 405.

CH, CH, CH, SiMe, H towards carbene (II) attack has shown (Table 1) that in both cases Si-H insertion is the

TABLE 1	
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Reaction of the carbene CHF₂ CF with vinylsilanes

	Products	Products (% yield) *			
Silane	Si-H Insertion	C=C Ad	C=C Addition		
CH ₂ :CH·SiMe ₂ H	(X) (93)	(XII)	(7)		
CH ₂ :CH·CH ₂ ·ŠiMe ₂ H	(XI) (67)	(XIII)	(33)		
* Determined by	repeated integration of	^{1}H and ^{19}F	n.m.r.		
spectra $(\pm 3\%)$.					

predominant, though not exclusive, reaction. The products (X)-(XIII) were characterised by ¹H and ¹⁹F n.m.r. spectroscopy since g.l.c. columns suitable for the complete separation of the products were not found. The cyclopropanes (XII) and (XIII) were both shown by



n.m.r. to be present as mixtures of cis- and trans-isomers (ratio 1:2) and, on the basis of the identified products from previously reported additions of carbene (II) to olefins,⁵ the *trans*-isomers are presumed to be the major components.

Since the carbene (II) rearrangement products were not detected in these reactions it is probable that the reactivities of the Si-H bonds towards insertion are of the cess. Such an explanation has been proposed previously to account for the low reactivity of the olefinic double bonds in trialkylvinylsilanes towards dichlorocarbene addition.^{16,17} These effects are greatest when the double bond is adjacent to silicon and decrease as the number of intervening CH₂ groups increases.

Reaction of the Carbene (II) with the Silanes Me_nSiCl_{4-n} (n = 0-3) and Me₃SiBr.—Decomposition of the carbene precursor (I) in the presence of an excess of each of the silanes SiCl₄, MeSiCl₃, Me₂SiCl₂, Me₃SiCl, and Me₃SiBr yielded products formed by insertion of the carbene (II) into a silicon-halogen bond (Table 2). In addition quantitative yields of silicon tetrafluoride together with the carbene rearrangement products trifluoroethylene and cis- and trans-(III) were obtained. Products arising from the insertion of carbene (II) into the C-H bonds of the chloromethylsilanes and bromotrimethylsilane were not detected.

The ¹H n.m.r. spectra of the insertion products all showed absorption at τ ca. 4.0 (CHF₂) and those which contained methyl groups showed absorptions in the region τ 9.0–9.95. The ¹⁹F n.m.r. spectra all showed absorption at ca. 46 p.p.m. (CHF₂, AB pattern) and absorption at either 73.5-74.5 (CFCl) or 77.0 p.p.m. (CFBr). The chemical shifts and coupling constants were in agreement with those determined previously for the same groups in similar compounds.18,19

The silane CHF₂·CFCl·SiCl₃ has been observed to undergo rearrangement on pyrolysis at 160 °C (20 h) to afford the silane $CHF_2 \cdot CCl_2 \cdot SiFCl_2$ (85%).²⁰ In the present work, however, no rearrangement by Cl-F exchange of this or any other adduct containing Si-Cl bonds shown in Table 2 was observed under the conditions employed (150 °C; 6 h).

The statistical yields of Si-Cl insertion products provide an indication of the relative reactivity of the Si-Cl

Products (% yield) Statistical yield of ŚiF₄ CF₂:CHF (III) Insertion product Silane insertion product * CHF₂·CFCl·SiCl₃ CHF₂·CFCl·SiCl₂Me CHF₂·CFCl·SiClMe₂ CHF₂·CFCl·SiMe₃ CHF₂·CFCl·SiMe₃ SiCl₄ 100 50 46 4 1 MeSiC1 100 45 45 10 3.3 Me2SiCl2 100 7.545 40 15 $\mathbf{2}$ 2 Me₃SiCl 100 54 44 8 38 8 CHF2 ·CFBr ·SiMe3 Me₃SiBr 100 54

TABLE 2 Reaction of the carbene CHF2. CF with halogenosilanes

* Based on the number of silicon-halogen bonds available for insertion.

same order as those of Si-H bonds in trialkylsilanes. The olefinic double bonds, however, show less reactivity towards addition by carbene (II) than those in hydrocarbon olefins. This is probably due mainly to a decrease in the nucleophilicity of the olefinic double bond caused by overlap of the π -cloud with vacant d orbitals on silicon and also to the destabilising effect of the electropositive silicon atom on the transition state of the addition probonds in the individual silanes towards insertion by (II). This order was found to be $Me_2SiCl_2 > MeSiCl_3 >$ $Me_3SiCl > SiCl_4$, and the Si-Br bond in bromotrimethylsilane was found to be ca. 4 times more reactive towards insertion than the Si-Cl bond in chlorotrimethylsilane.

Mechanisms involving a radical abstraction process or

¹⁸ W. I. Bevan, R. N. Haszeldine, J. Middleton, and A. E. Tipping, unpublished results.

 J. Dyer and J. Lee, Spectrochim. Acta, 1970, 26A, 1045.
 T. L. Cottrell, 'The Strengths of Chemical Bonds,' 2nd edn., Butterworths, London, 1958.

¹⁶ J. Cudlin and V. Chvalovský, Coll. Czech. Chem. Comm., 1962, 27. 1658; 1963, 28, 3088. ¹⁷ D. Seyferth and H. Dertouzos, J. Organometallic Chem.,

^{1968, 11, 263.}

initial nucleophilic attack on the silicon atoms of the halogenosilanes are unlikely because the expected order of reactivity for both processes, $SiCl_4 > MeSiCl_3 >$ $Me_2SiCl_2 > Me_3SiCl$, was not observed. It is thus probable that the insertions involve initial electrophilic attack by carbene (II) at the chlorine atom followed closely by interaction of the filled sp^2 orbital of the singlet carbone with the d orbital system of the silicon atom to afford a three-centre transition state (XIV).



The activation energy for formation of the transition state (XIV) would be expected to be greater than that for formation of the corresponding Si-H transition state on account of the higher Si-Cl bond strength (ca. 91

which breaks down to afford the observed products.22,25 In addition many of these reactions were carried out in the presence of copper powder or copper salts and it has recently been reported that the intermediacy of a free carbene is doubtful in such reactions.²⁶

Reaction of the Carbene (II) with Silanes containing both Si-H and Si-Cl Bonds.-The insertion products obtained from decomposition of the carbene precursor (I) at 150 °C (6 h) in the presence of a 2.5:1 molar ratio of dimethylchlorosilane, methyldichlorosilane, or trichlorosilane are shown in Table 3. In all cases a quantitative yield of silicon tetrafluoride and products resulting from rearrangement of the carbene (II) was also obtained.

Differentiation between products containing the grouping CHF₂·CFCl·Si, *i.e.* Si-Cl insertion products, and those containing the grouping CHF₂·CHF·Si, *i.e.* Si-H insertion products, was achieved by n.m.r. and i.r. spectroscopy. The former products showed a strong i.r. absorption at ca. 4.6 µm (Si-H str.) and characteristic ¹⁹F n.m.r. absorption at ca. 76 p.p.m. (relative to trifluoroacetic

TABLE 3

Reaction of the carbene (II) with silanes containing both Si-H and Si-Cl bonds							
	Insertion products				Statistical ratio of insertion products		
Silane	Si-H	%	Si-Cl	%	(Si-H : Si-Cl) *		
Me _s ClSiH	CHF, CHF.SiClMe,	96		†	~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~~		
MeCl_SiH	CHF, CHF SiCl, Me	29	CHF, CFCl·SiHClMe ‡	29	2:1		
Cl.SiH	CHF, CHF SiCl,	10	CHF, CFCl·SiHCl,	43	0.8:1		

* Based on number of Si-H and Si-Cl bonds available. † Less than 2% would have been detected. ‡ Two isomers present in ratio 1:1.

kcal mol⁻¹) as compared with the Si-H bond strength (ca. 76 kcal mol⁻¹).²⁰

Cl_aSiH

The anomalous position of chlorotrimethylsilane in the reactivity order is difficult to explain. The covalent radii of the chlorine atom and the methyl group are approximately the same ²¹ and so the factors determining the low reactivity are probably the exact Si-Cl bond strength and the Cl-Si-Me bond angle; detailed information on these is not available. Although the Si-Br bond in bromotrimethylsilane is ca. four times more reactive towards insertion by the carbene (II) than the Si-Cl bond in chlorotrimethylsilane, the relatively low Si-Br bond strength 22 (ca. 74 kcal mol-1) would be expected to result in a much higher yield of insertion product than observed.

The reactions of diazomethane with a variety of metal halides have been reported previously, and with the chlorosilanes investigated products formed by insertion of a CH₂ group into the Si-Cl bond were isolated.²³ Similar results were later obtained by other workers,^{22,24} but it is probable that these reactions do not involve free methylene but rather a diazomethane-silicon complex

²¹ L. Pauling, 'The Nature of the Chemical Bond,' 3rd edn., Cornell University Press, Ithaca, New York, 1960.
²² R. A. Shaw, J. Chem. Soc., 1957, 2831.
²³ A. Ya. Yakubovich, S. P. Makarov, V. A. Ginsburg, G. I.

Gavrilov, and E. N. Merkulova, *Doklady Akad. Nauk S.S.S.R.*, 1950, 72, 69; A. Ya. Yakubovich and V. A. Ginsburg, J. Gen. Chem. (U.S.S.R.), 1952, 22, 1783.

acid) assigned to the CFCl group, whereas the latter showed no i.r. absorption band at ca. $4.6 \,\mu\text{m}$ but the ¹⁹F n.m.r. spectra showed an absorption at ca. 157 p.p.m. assigned to CHF ($J_{\rm FH}$ ca. 45.5 Hz).

The reactivity of the Si-H bond in the silanes decreases as methyl groups are successively replaced by chlorine. It is interesting that the silane Me₂ClSiH affords only the Si-H insertion product and the yield of this compound (96%) indicates that a single chlorine atom does not appreciably deactivate the Si-H bond towards insertion by carbene (II) as compared with the trialkylsilanes studied (yields 98-99%). However, when two or three chlorine atoms are present, *i.e.* in the silanes MeCl_SiH and Cl₃SiH, considerable deactivation of the Si-H bond towards insertion is observed. This deactivation is probably due to (i) the strong -I inductive effect of chlorine which decreases the electron density at the Si-H bond, thus rendering it less susceptible to electrophilic attack by the carbene (II) and (ii) increased steric inhibition to attack on Si-H.

As the reactivity of the Si-H bond towards insertion decreases, a corresponding increase in the reactivity of the Si-Cl bonds towards insertion is observed. The

²⁴ D. Seyferth and E. G. Rochow, J. Amer. Chem. Soc., 1955, 77, 907; K. Kramer and A. N. Wright, Chem. Ber., 1963, 96, 1877. ²⁶ D. Seyferth, Chem. Rev., 1955, 55, 1155. ²⁸ E. Muller, H. Kessler, and B. Zech, Fortschr. Chem. Forsch.,

^{1966, 7, 128;} W. R. Moser, J. Amer. Chem. Soc., 1969, 91, 1135 and 1141.

yields of Si-Cl insertion products obtained with the silanes $MeCl_2SiH$ and Cl_3SiH (29 and 43%, respectively) are appreciably higher than those obtained from silanes $Me_{4-n}SiCl_n$ containing only Si-Cl and Si-Me linkages (2-15%). The replacement of a methyl group or a chlorine atom by the smaller hydrogen atom thus apparently enables the carbene (II) to approach the Si-Cl bond more easily and also results in a decrease in steric hindrance in the transition state. These factors thus allow insertion into the Si-Cl bond to compete effectively with insertion into the deactivated Si-H bond in the silanes $MeCl_2SiH$ and Cl_3SiH .

The observation that carbene (II) inserts into both the Si-H and Si-Cl bonds of dichloro(methyl)silane and trichlorosilane is in contrast to the copper-catalysed decomposition of diazomethane in the presence of trichlorosilane which afforded the Si-Cl insertion product only.²⁵

Reaction of the Carbene (II) with Trichloro(vinyl)silane. -This reaction was investigated in order to determine whether Si-Cl insertion by the carbene (II) could compete successfully with carbene addition to the olefinic double bond. Decomposition of the carbene precursor (I) at 150 °C (6 h) in the presence of an excess of trichloro-(vinyl)silane (3 : 1 molar ratio) gave silicon tetrafluoride (100%), trifluoroethylene (34%), and a mixture of *cis*and trans-1-difluoromethyl-1-fluoro-2-trichlorosilylcyclopropane (66%) in the ratio 1:2. Products formed by insertion of the carbene (II) into an Si-Cl bond were not detected. The assignments of the cis- and transstructures to the separated isomers were made on the basis of the ¹⁹F n.m.r. spectra: the absorption of the tertiary fluorine in the *cis*-isomer is at considerably lower field (110.8 p.p.m.) than that in the *trans*-isomer (127.5) p.p.m.) because of the greater deshielding effect of the trichlorosilyl group when it is *cis* to the fluorine. The observed cis: trans ratio of 1:2 compares well with the same ratio of cis- and trans-cyclopropanes formed in the reaction of the carbene (II) with the but-2-enes⁵ and with dimethylvinylsilane and allyldimethylsilane.

The yield of cyclopropanes obtained in the present reaction (66%) is considerably lower than those obtained from reactions of the carbene (II) with hydrocarbon olefins.⁵ This deactivation of the double bond towards carbene (II) addition is probably due to the same factors as put forward to explain the decreased reactivities of dimethylvinylsilane and allyldimethylsilane (see earlier).

EXPERIMENTAL

Reactants and products were manipulated, where possible, in a conventional vacuum system in order to avoid contamination with air or moisture. Reactions involving the decomposition of 1,1,2,2-tetrafluoroethyltrifluorosilane (I), were carried out in Pyrex bulbs (capacity *ca.* 2, 3, or 5 l) fitted with a side arm, at pressures of *ca.* 1 atm. Pure compounds were isolated by repeated fractional condensation *in vacuo* or by preparative scale g.l.c. [Pye 105 or Perkin-Elmer 452 instrument with 2—10 m columns packed with Silicone SE 30 or MS 550 oil, dinonyl phthalate, or Apiezon L grease (10-25%) on Celite or Chromosorb W]. The identities of products were established by elemental analysis, i.r. spectroscopy (Perkin-Elmer spectrophotometer model 452 with sodium chloride optics), mass spectrometry (A.E.I. MS/2 instrument), and n.m.r. spectroscopy (Perkin-Elmer R10 instrument operating at 60.0 MHz for ¹H and 56.46 MHz for ¹⁹F, or a Varian HA100 spectrometer operating at 100.0 MHz for ¹H and 94.1 MHz for ¹⁹F). Tetramethylsilane was used as reference for ¹H spectra and trifluoroacetic acid as reference for ¹⁹F spectra. For compounds marked with an asterisk, detailed n.m.r. and i.r. data are available in Supplementary Publication No. SUP 21095 (12 pp., 1 microfiche).[†] A double asterisk indicates that n.m.r. data only are available.

1,1,2,2-Tetrafluoroethyltrifluorosilane was prepared by the method reported previously.^{3,4} Other starting materials not available commercially were prepared *via* literature methods and were carefully purified before use.

Decomposition of 1,1,2,2-Tetrafluoroethyltrifluorosilane (I) in the Presence of Silanes.—(a) Triethylsilane. A mixture of triethylsilane (10.40 g, 90.0 mmol) and the silane (I) (5.58 g, 30.0 mmol), heated at 150° (6 h), gave (i) silicon tetrafluoride (3.12 g, 30.0 mmol, 100%), (ii) trifluoroethylene (0.05 g, 0.60 mmol, 2%), (iii) unchanged triethylsilane (7.0 g, 60.5 mmol, 67% recovered), and (iv) triethyl-(1,2,2-trifluoroethyl)silane * (5.82 g, 29.4 mmol, 98%) (Found: C, 48.1; H, 8.4. $C_8H_{17}F_3Si$ requires C, 48.4; H, 8.6%), b.p. 169— 170°.

(b) Diethylmethylsilane. A mixture of diethylmethylsilane (10·20 g, 90·0 mmol) and the silane (I) (5·58 g, 30·0 mmol), heated at 150° (6 h), gave (i) silicon tetrafluoride (3·12 g, 30·0 mmol, 100%), (ii) trifluoroethylene (0·05 g, 0·60 mmol, 2%), (iii) unchanged diethylmethylsilane (6·16 g, 60·5 mmol, 67% recovered), and (iv) diethylmethyl-(1,2,2-trifluoroethyl)silane * (5·42 g, 29·4 mmol, 98%) (Found: C, 45·7; H, 8·2. C₇H₁₅F₃Si requires C, 45·6; H, 8·2%), b.p. 142°.

(c) Trimethylsilane. A mixture of trimethylsilane (6.67 g, 90.0 mmol) and the silane (I) (5.58 g, 30.0 mmol), heated at 150° (6 h), gave (i) silicon tetrafluoride (3.12 g, 30.0 mmol, 100%), (ii) trifluoroethylene (0.02 g, 0.30 mmol, 1%), (iii) unchanged trimethylsilane (4.44 g, 60.0 mmol, 67% recovered), and (iv) trimethyl-1,2,2-trifluoroethylsilane ** (4.64 g, 29.7 mmol, 99%) (Found: C, 38.6; H, 6.9. Calc. for $C_5H_{11}F_3Si:$ C, 38.4; H, 7.0%), b.p. 82—83°, the i.r. spectrum of which was identical with that of a previously prepared sample.⁹

(d) Deuteriotrimethylsilane. A mixture of deuteriotrimethylsilane (1.72 g, 23.0 mmol) and the silane (I), heated at 150° (6 h), gave (i) silicon tetrafluoride (2.49 g, 23.0 mmol, 100%), (ii) trifluoroethylene (0.23 g, 2.8 mmol, 12%), (iii) unchanged deuteriotrimethylsilane (0.21 g, 2.8 mmol, 12%) recovered), and (iv) 1-deuterio-1,2,2-trifluoroethyltrimethylsilane * (3.17 g, 20.2 mmol, 88%) (Found: C, 38.2; H + D, 7.7. C₅H₁₀DF₃Si requires C, 38.2; H + D, 7.7%), b.p. 95°.

(e) Dimethyl(vinyl)silane. A mixture of dimethyl(vinyl)silane (7.74 g, 90.0 mmol) and the silane (I) (6.94 g, 37.3 mmol), heated at 150° (6 h), gave (i) silicon tetrafluoride (3.88 g, 37.3 mmol, 100%), (ii) unchanged dimethyl(vinyl)silane (4.55 g, 52.9 mmol, 59% recovered), and (iii) a fraction (6.42 g, 37.1 mmol, 99.5%) (Found: C, 43.1; H, 6.6. Calc.

[†] For details of Supplementary Publications, see Notice to Authors No. 7 in *J.C.S. Perkin I*, 1973, Index issue.

for $C_6H_{11}F_3Si: C, 42.8$; H, 6.5%) which was shown by g.l.c. and n.m.r. spectroscopy to consist of a major component A (93%) and two isomeric compounds B and C (7%). The components could not be separated completely by preparative-scale g.l.c. on a number of different columns. Component A was identified by n.m.r. spectroscopy as dimethyl-(1,2,2-trifluoroethyl)vinylsilane.** Components B and C were identified as the *cis*- and *trans*-isomers ** of 1-diffuoromethyl-2-dimethylsilyl-1-fluorocyclopropane in the ratio 1:2.

(f) Allyldimethylsilane. A mixture of allyldimethylsilane (9.0 g, 90.0 mmol) and the silane (I) (6.94 g, 37.3mmol), heated at 150° (6 h), gave (i) silicon tetrafluoride (3.88 g, 37.3 mmol, 100%), (ii) unchanged allyldimethylsilane (5.30 g, 53.0 mmol, 59% recovered), and (iii) a fraction (6.73 g, 37.0 mmol, 99%) (Found: C, 46.1; H, 7.2. Calc. for $C_7H_{13}F_3Si$: C, 46·1; H, 7·2%) which was shown by g.l.c. and n.m.r. spectroscopy to consist of a major component D (66.5%) and two isomeric compounds E and F (32.5%); an attempted separation of the components by preparativescale g.l.c. on a variety of columns was unsuccessful. Component D was identified as allyldimethyl-(1,2,2-trifluoroethyl)silane.** Components E and F were identified as cisand trans-1-difluoromethyl-2-(dimethylsilylmethyl)-1-fluorocyclopropane,** respectively, and were present in the ratio 1:2.

(g) Silicon tetrachloride. A mixture of silicon tetrachloride (15·30 g, 90·0 mmol) and the silane (I) (6·96 g, 37·5 mmol), heated at 150° (6 h), gave (i) silicon tetrafluoride (3·79 g, 37·5 mmol, 100%), (ii) trifluoroethylene (1·51 g, 18·4 mmol, 50%), (iii) a mixture (1·38 g, 8·4 mmol, 46%) of cisand trans-1-difluoromethyl-1,2,2,3-tetrafluorocyclopropane which was identified by a comparison of its i.r. spectrum with that of an authentic sample of the mixture of isomers, (iv) unchanged silicon tetrachloride (15·10 g, 88·5 mmol, 98% recovered), and (v) trichloro-(1-chloro-1,2,2-trifluoroethyl)silane (0·36 g, 1·4 mmol, 4%) (Found: C, 9·4; H, 0·5. Calc. for C₂HCl₄F₃Si: C, 9·5; H, 0·4%), b.p. 119° (lit.,²⁷ 116—118°), identified by a comparison of its ¹H and ¹⁹F n.m.r. spectra with those reported.^{18,19}

(h) Trichloro(methyl)silane. A mixture of trichloro-(methyl)silane (13.45 g, 90.0 mmol) and the silane (I) (6.50 g, 35.0 mmol), heated at 150° (6 h), gave (i) silicon tetrafluoride (3.64 g, 35.0 mmol, 100%), (ii) trifluoroethylene (1.29 g, 15.7 mmol, 45%), (iii) a mixture of cis- and trans-1-difluoromethyl-1,2,2,3-tetrafluorocyclopropane (1.30 g, 7.9 mmol, 45%), (iv) unchanged trichloro(methyl)silane (12.9 g, 86.5 mmol, 96% recovered), and (v) dichloro-(1-chloro-1,2,2-trifluoroethyl)methylsilane * (0.79 g, 3.4 mmol, 10%) (Found: C, 15.2; H, 1.8. $C_3H_4Cl_3F_3Si$ requires C, 15.5; H, 1.7%), b.p. 115°.

(j) Dichlorodimethylsilane. A mixture of dichlorodimethylsilane (11.60 g, 90.0 mmol) and the silane (I) (6.96 g, 37.5 mmol), heated at 150° (6 h), gave (i) silicon tetra-fluoride (3.90 g, 37.5 mmol, 100%), (ii) trifluoroethylene (1.39 g, 16.9 mmol, 45%), (iii) a mixture of cis- and trans-1-difluoromethyl-1,2,2,3-tetrafluorocyclopropane (1.23 g, 7.5 mmol, 40%), (iv) unchanged dichlorodimethylsilane (10.90 g, 84.4 mmol, 93% recovered), and (v) chloro-(1-chloro-1,2,2-trifluoroethyl)dimethylsilane * (1.19 g, 5.6 mmol, 15%) (Found: C, 22.7; H, 3.5. C₄H₇Cl₂F₃Si requires C, 22.8; H, 3.3%), b.p. 135°.

(k) Chlorotrimethylsilane. A mixture of chlorotrimethylsilane (9.76 g, 90.0 mmol) and the silane (I) (6.53 g, 35.1 mmol), heated at 150° (6 h), gave (i) silicon tetrafluoride (3.65 g, 35.1 mmol, 100%), (ii) trifluoroethylene (1.55 g, 19.0 mmol, 54%), (iii) a mixture of *cis*- and *trans*-1-difluoromethyl-1,2,2,3-tetrafluorocyclopropane (1.26 g, 7.7 mmol, 44%), (iv) unchanged chlorotrimethylsilane (9.66 g, 89.0 mmol, 99% recovered), and (v) (1-*chloro*-1,2,2-*trifluoroethyl*)*trimethylsilane* * (0.15 g, 0.75 mmol, 2%) (Found: C, 31.8; H, 5.4. C₅H₁₀ClF₃Si requires C, 31.5; H, 5.3%), b.p. 128°.

(1) Bromotrimethylsilane. A mixture of bromotrimethylsilane (13.80 g, 90.0 mmol) and the silane (I) (6.80 g, 36.6 mmol), heated at 150° (6 h), gave (i) silicon tetrafluoride (3.80 g, 36.6 mmol, 100%), (ii) trifluoroethylene (1.62 g, 19.7 mmol, 54%), (iii) a mixture of *cis*- and *trans*-1-difluoromethyl-1,2,2,3-tetrafluorocyclopropane (1.15 g, 7.0 mmol, 38%), (iv) unchanged bromotrimethylsilane (13.32 g, 87.2 mmol, 97% recovered), and (v) (1-bromo-1,2,2-trifluoroethyl)trimethylsilane * (0.64 g, 2.7 mmol, 8%) (Found: C, 26.0; H, 4.7. $C_5H_{10}BrF_3Si$ requires C, 25.5; H, 4.3%), b.p. 145°.

(m) Chlorodimethylsilane. A mixture of chlorodimethylsilane (8.60 g, 90.0 mmol) and the silane (I) (6.96 g, 37.5 mmol), heated at 150° (6 h), gave (i) silicon tetrafluoride (3.90 g, 37.5 mmol, 100%), (ii) trifluoroethylene (0.14 g, 1.7 mmol, 4.5%), (iii) unchanged chlorodimethylsilane (5.12 g, 54.2 mmol, 60% recovered), and (iv) chlorodimethyl-(1,2,2trifluoroethyl)silane * (6.32 g, 35.8 mmol, 95.5%) (Found: C, 27.4; H, 4.7. $C_4H_8ClF_3Si$ requires C, 27.2; H, 4.5%), b.p. 109°.

(n) Dichloro(methyl)silane. A mixture of dichloro-(methyl)silane (10.35 g, 90.0 mmol) and the silane (I) (6.96 g, 37.5 mmol), heated at 150° (6 h), gave (i) silicon tetrafluoride (3.90 g, 37.5 mmol, 100%), (ii) trifluoroethylene (0.65 g, 8.0 mmol, 21%), (iii) a mixture of cis- and trans-1difluoromethyl-1,2,2,3-tetrafluorocyclopropane (0.56 g, 3.4 mmol, 18%), (iv) unchanged dichloro(methyl)silane (7.83 g, 68.0 mmol, 76% recovered), and (v) a fraction (4.30 g, 21.8 mmol) mmol, 58%) which was separated by g.l.c. (8 m Silicone MS 550 at 98°) into its two components, identified as (a) dichloro(methyl)-1,2,2-trifluoroethylsilane ** (2.15 g, 10.9 mmol, 29%) (Found: C, 17.8; H, 2.4. Calc. for C₃H₅Cl₂-F₃Si: C, 18.3; H, 2.5%), b.p. 114° (lit., ⁹ b.p. 113-114°) and (b) chloro-(1-chloro-1,2,2-trifluoroethyl)methylsilane * (2.15 g, 10.9 mmol, 29%) (Found: C, 18.1; H, 2.2%), b.p. 104-105°, and present as two stereoisomers in the ratio 6:5(n.m.r.).

(o) Trichlorosilane. A mixture of trichlorosilane (12·2 g, 90·0 mmol) and the silane (I) (6·95 g, 37·4 mmol), heated at 150° (6 h), gave (i) silicon tetrafluoride (3·88 g, 37·4 mmol, 100%), (ii) trifluoroethylene (0·76 g, 9·3 mmol, 25%), (iii) a mixture of cis- and trans-1-difluoromethyl-1,2,2,3-tetra-fluorocyclopropane (0·67 g, 4·1 mmol, 22%), (iv) unchanged trichlorosilane (9·50 g, 70·0 mmol, 78% recovered), and (v) a fraction (4·31 g, 19·8 mmol, 53%) which was separated by g.l.c. (8 m Silicone MS 550 at 90°) into its two components, identified as (a) dichloro-(1-chloro-1,2,2-trifluoroethyl)silane * (3·48 g, 16·0 mmol, 43%) (Found: C, 10·9; H, 1·1. C₂H₂Cl₃F₃Si requires C, 11·0; H, 0·9%), b.p. 97°, and (b) trichloro-1,2,2-trifluoroethylsilane (0·83 g, 3·8 mmol, 10%) (Found: C, 11·3; H, 1·1%), b.p. 104° (lit., 9 104°), i.r. and n.m.r. spectra identical with those previously found.^{18,19}

(p) Trichloro(vinyl)silane. A mixture of trichloro(vinyl)silane (9.70 g, 60.0 mmol) and the silane (I) (3.90 g, 21.0 mmol), heated at 150° (6 h), gave (i) silicon tetrafluoride (2.18 g, 21.0 mmol, 100%), (ii) trifluoroethylene (0.59 g, 7.2 mmol, 34%), (iii) unchanged trichloro(vinyl)silane (6.30 g,

²⁷ G. W. R. Puerekhauer, Diss. Abs., 1957, 17, 40.

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39.0 mmol, 65% recovered), and (iv) a fraction (3.35 g, 13.8 mmol, 66%) which was separated by g.l.c. (8 m Silicone MS 550 at 135°) into its two components (a) trans-1-difluoro-methyl-1-fluoro-2-trichlorosilylcyclopropane * (2.23 g, 9.2 mmol, 44%) (Found: C, 20.1; H, 1.9. $C_4H_4Cl_3F_3Si$ re-

quires C, 19.7; H, 1.7%), b.p. 153°, and (b) cis-1-difluoromethyl-1-fluoro-2-trichlorosilylcyclopropane * (1.12 g, 4.6 mmol, 22%) (Found: C, 20.1; H, 2.0%), b.p. 156°.

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